

Effect of O₂ addition during magnetron sputtering deposition on the growth and chemistry of Ag thin films

Supplemental document

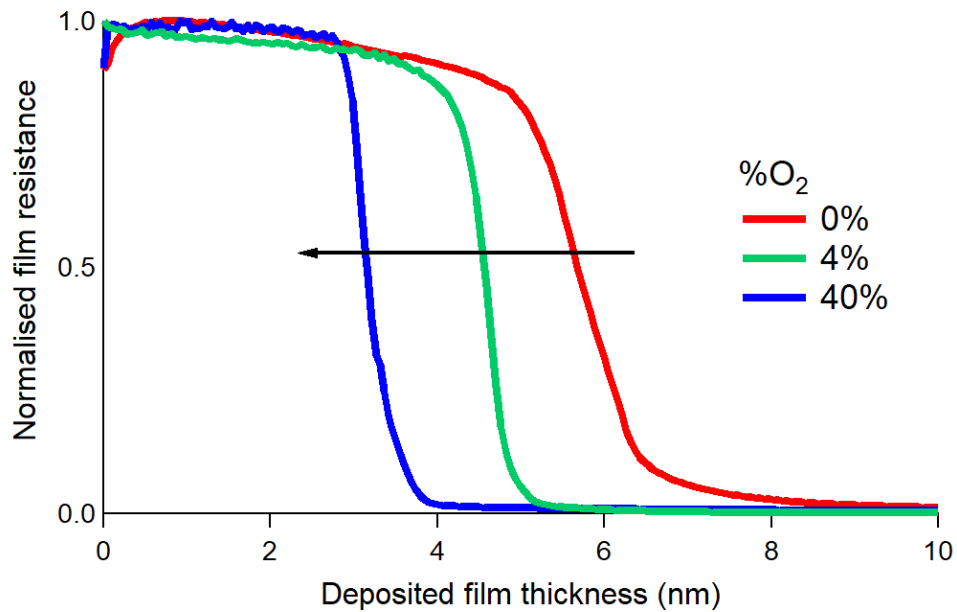


Figure-A. Diminution of the percolation threshold thickness with increasing %O₂ during deposition.

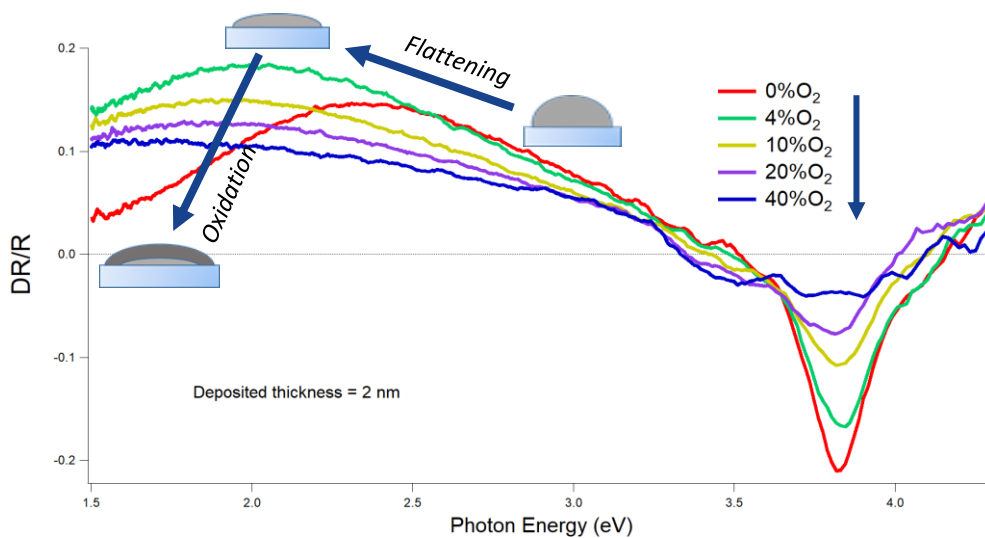


Figure-B. SDRS spectra for a nominal deposited film thickness of 2 nm. Information on different characteristics of the Ag nanoparticles (aspect ratio, oxidation state...) are inferred from trends in the SDRS spectra, based on simulations results with the *Granfilm* software.